

## AUTHOR INDEX

- Abidzina, Volha, 183  
 Araki, Rei, 177  
 Armbrister, Vladislav, 131  
 Arora, Brij M., 213  
 Avasthi, Devesh K., 109, 213
- Baglin, John E.E., 39  
 Barabash, R., 21  
 Battaglin, Giancarlo, 125  
 Bello, Valentina, 125  
 Bernas, Harry, 101  
 Bottcher, T., 21  
 Budak, Satilmis, 91, 145, 151, 171,  
 183, 189, 201, 207
- Calzzani, F., 165  
 Carey, J.D., 109  
 Chai, Guangyu, 221  
 Chhay, B., 91, 145, 151, 165  
 Chow, Lee, 221  
 Chu, Paul K., 81  
 Chung, J.-S., 21
- Dhamodaran, S. 213  
 Dvurechenskii, Anatoly, 131
- Elkin, I., 183  
 Eltem, Rengin, 91  
 Espiau de Lamaestre, Roch, 101  
 Ezdesir, Ayhan, 91
- Filip, L.D., 109  
 Findikoglu, Alp T., 49  
 Frommer, Jane E., 39
- Giannuzzi, Lucille A., 15  
 Golovchenko, Jene A., 29  
 Gorelick, Sergey, 67  
 Groetzschel, Reiner, 131  
 Guner, S., 171, 189, 201, 207  
 Gurhan, Ismet, 75  
 Gutakovskii, Anton, 131  
 Gutowski, J., 21
- Hernandez-Vélez, Manuel, 55
- Hjort, Klas, 55  
 Hommel, D., 21  
 Hoogerheide, David P., 29  
 Hubert, Dominique H.W., 15
- Ice, G., 21  
 ILA, Daryush, 75, 91, 145, 151,  
 165, 171, 183, 189, 201, 207,  
 231
- Jensen, Jens, 55
- Kawashita, Masakazu, 159, 177  
 Kaya, Nusret, 91, 151  
 Kellock, Andrew J., 39  
 Kesler, Valery, 131  
 Kirienko, Victor, 131  
 Kishimoto, N., 115  
 Kroger, R., 21  
 Kumar, Amit, 109
- Laitinen, Mikko, 67  
 Lin, Cheng-lu, 195  
 Liu, W., 21  
 Liu, Xuanyong, 81  
 Lohmeyer, H., 21
- Majumdar, Subrata, 137  
 Matias, Vladimir, 49  
 Matsui, Yoshinori, 61  
 Mattei, Giovanni, 125  
 Maurizio, Chiara, 125  
 Mazzoldi, Paolo, 125  
 Minamisawa, Renato Amaral, 189,  
 201, 231  
 Miyoshi, Nozomi, 61  
 Muntele, Claudiu, 91, 151, 171,  
 183, 189, 201, 207, 231
- Nikolaev, Alexey, 91, 151  
 Novikov, Pavel, 131
- Okada, Takeshi, 159  
 Oks, Efim, 91, 151  
 Oshima, Akihiro, 61

Cambridge University Press

978-1-107-40865-4 - Ion-Beam-Based Nanofabrication: Materials Research Society

Symposium Proceedings: Volume 1020

Editors: Daryush ILA, John Baglin, Naoki Kishimoto and Paul K. Chu

Index

[More information](#)

- Oztarhan, Ahmet, 91, 151, 165
- Pan, Jin, 115
- Paramanik, Dipak, 137
- Pathak, Anand P., 213
- Pellegrini, Giovanni, 125
- Pivin, J.C., 109
- Possnert, Göran, 55
- Puttaraksa, Nitipon, 67
- Qian, Cong, 195
- Red'ko, V., 183
- Roussel, Laurent, 15
- Sahoo, Smruti Ranjan, 137
- Saito, K., 115
- Sajavaara, Timo, 67
- Sanz, Ruy, 55
- Sathish, N., 213
- Sebald, K., 21
- Seki, Shu, 61
- Sheehan, Chris, 49
- Skupinski, Marek, 55
- Smagina, Zhanna, 131
- Smith, C.C., 171, 189, 201, 207
- Stepina, Nataly, 131
- Stokes, Debbie J., 15
- Tagawa, Seiichi, 61
- Takaoka, Gikan H., 159, 177
- Takeda, Y., 115
- Tek, Zekai, 91
- Tereshko, I., 183
- Tihminlioglu, Funda, 91, 151
- Toyoda, Noriaki, 3
- Tripathi, A., 109
- Turos, Andrzej, 213
- Urkac, Emel Sokullu, 91, 151
- Varma, Shikha, 137
- Walker, D., 183
- Wang, H., 115
- Washio, Masakazu, 61
- Whitlow, Harry J., 67
- Wilhelmi, Oliver, 15
- Yamada, Isao, 3
- Yenigul, Mesut, 91
- Zhang, Feng, 195
- Zhang, Zheng-xuan, 195
- Zheng, Bangke, 145, 171
- Zimmerman, Robert Lee, 75, 91, 145, 165, 171, 189, 201, 207, 231

**SUBJECT INDEX**

- absorption, 183
- adhesion, 75
- Au, 183
  
- biomaterial, 75, 81
- biomedical, 177
  
- cellular (material form), 75
- chemical vapor deposition (CVD)
  - (deposition), 213
- cluster assembly, 101
- coating, 81
  
- devices, 221
- diffusion, 29
  
- field emission, 109, 221
- film, 49
  
- Ge, 131
  
- ion-beam
  - assisted deposition, 49, 131, 137, 171, 189, 201, 207
  - processing, 3, 15, 21, 39, 61, 67, 101, 165, 177, 221, 231
- ion-implantation, 91, 115, 125, 151, 195
- ion-solid interactions, 3, 29, 55, 109, 159
  
- lithography (removal), 39, 55, 61, 67
  
- microelectronics, 3
  
- nanoscale, 15, 39, 91, 115, 145, 151, 183
- nanostructure, 15, 29, 109, 125, 131, 137, 165, 171, 189, 195, 201, 207, 231
- nucleation and growth, 101
  
- optical properties, 125
  
- particulate, 115
- plasma deposition, 81
- polymer, 61, 165, 231
- polymerization, 91, 151
  
- radiation effects, 213
- Rutherford backscattering (RBS), 145
  
- scanning probe microscopy (SPM), 137
- self-assembly, 55
- Si, 159
- simulation, 67
- surface reaction, 159, 177
  
- texture, 49
- thermal conductivity, 145
- thermoelectricity, 171, 189, 201, 207
- III-V, 21
  
- x-ray
  - diffraction (XRD), 21, 213
  - photoelectron spectroscopy (XPS), 195